

Molecular Precursors for the Electrodeposition of 2D-Layered Metal Chalcogenides for Next Generation Electronics

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Abstract

Two-dimensional transition metal dichalcogenides (TMDCs) are highly anisotropic layered semiconductors, with general formula ME_2 (M = metal, E = sulfur, selenium or tellurium). Much current research focusses on TMDCs for catalysis and energy applications; they are also attracting great interest for next-generation transistor and optoelectronic devices. These high-tech applications place stringent requirements on the stoichiometry, crystallinity, morphology and electronic properties of mono-/few-layer materials. As a solution-based process, where the material grows specifically on the electrode surface, electrodeposition offers great promise as a readily-scalable, area-selective growth process. This review explores the state-of-the-art for TMDC electrodeposition, highlighting how the choice of precursor(s), solvent, with novel 'device-ready' electrode geometries, influence their morphologies and properties, thus enabling the direct growth of ultra-thin, highly anisotropic 2D TMDCs and much scope for future advances.

[H1] Introduction

Semiconductors are integral to modern technology and the chips that provide the processing power that drive the devices that modern society relies on, such as smartphones, tablets, and PCs. Each chip contains billions of semiconducting transistors. The demand for smaller, faster and lower power devices places an ever-increasing demand on the development of nanoscale semiconductors.

2D-Layered transition metal dichalcogenides (TMDCs) are an exciting class of highly tunable and anisotropic semiconductors with considerable promise for implementation into next generation electronic and optical devices with novel architectures.¹⁻⁵ TMDCs have the general formula, ME_2 (M = transition metal, especially Mo, W, Ti, Zr, Nb, Ta; E = chalcogen, *i.e.* sulfur, selenium or tellurium) (Figure 1); the notation, MX_2 , where X = chalcogen = S, Se, Te, is also used by some communities. They adopt

32 layered structures, and each of the monolayers consists of 2D hexagonally packed E-M-E structures
33 (Figure 1a), where the metal atoms in the centre of the hexagonal plane are covalently bonded to the
34 chalcogen atoms above and below this plane. In a TMDC each metal atom is coordinated by six
35 chalcogens in either an octahedral or trigonal prismatic arrangement (Figure 1b). The monolayers are
36 stacked through van der Waals (vdW) interactions to form bulk TMDCs, with the formation of a variety
37 of polymorphs and polytypes dependant on the stacking sequence. The M-E-M bonding within the
38 layers is strong (covalent), while there is weak E...E vdW bonding between the layers. These layered
39 TMDCs exhibit extraordinary and unique layer-dependent physical properties when scaled down to
40 thicknesses of only a few-layers, or even a single monolayer. Their unique combination of robust intra-
41 layer bonds and weaker inter-layer bonding contributes to the distinct and highly anisotropic
42 properties of TMDC materials. This means their electronic structures can be engineered through
43 carefully controlling the number of layers, crystal phase, heterostructures and composition (for
44 instance, the choice of metal and chalcogen). These versatile and highly tunable properties, together
45 with the range of TMDCs that can exist, continue to attract a great deal of fundamental and
46 technological research in fields ranging from electronics,⁶⁻⁸ optoelectronics,⁹⁻¹¹ sensing¹² and
47 catalysis,^{13,14} to energy storage (batteries, supercapacitors)¹⁵⁻¹⁸ and energy generation (photovoltaics,
48 thermoelectric generators).¹⁹⁻²¹

49 Mechanical and liquid phase exfoliation (delamination from a bulk crystal) are commonly-used to
50 prepare mono- and few-layer single crystalline TMDC flakes.^{22,23} This approach has been instrumental
51 in revealing the unique properties of TMDCs, including their light-matter interactions, and many of
52 the novel electronic and optical device structures that have been demonstrated.^{6,24} However, these
53 methods are slow and require special care to avoid damage to the material, hence they are not
54 suitable for producing devices on the scale necessary for mass-production in industry.

55 Production of mono-/few-layer TMDCs requires scalable and, ideally, **area-selective [G]** deposition
56 techniques that deliver the TMDC only onto or into specific pre-patterned regions of a wafer substrate.
57 Chemical vapour deposition (CVD),²⁵⁻²⁷ atomic layer deposition (ALD),^{28,29} and molecular beam epitaxy
58 (MBE)^{30,31} are currently the most common processing methods for the large-scale production of mono-
59 and few-layer TMDCs. They can give high crystal quality, controllable thickness, and excellent
60 electronic properties at full wafer-scale. A wide range of monolayer and thin film TMDCs, such as
61 MoS₂, WS₂, WSe₂, VTe₂, have been obtained this way.^{9,32} These methods have also been used to
62 deposit TMDC heterostructures, such as WSe₂/MoS₂, WSe₂/MoSe₂ and MoS₂/WS₂.³³⁻³⁵ However, they
63 also have some drawbacks. For example, it is very challenging to grow large, single crystalline domain
64 TMDC layers with these methods. This is because they typically produce multiple nuclei on the

65 substrate simultaneously, hence the as-deposited materials are polycrystalline; the crystallinity can
66 be increased by annealing at high temperatures.

67 It is also important to note that these growth methods are (usually) not area-selective. For TMDCs
68 grown on wafer-scale, various post-deposition processing steps, such as etching and patterning, are
69 therefore required to create the necessary nanoscale dimensions and architectures.³⁶ Such processes
70 are time-consuming, expensive and can introduce contamination and defects, which are detrimental
71 to the material quality and functionality. The current processes that are carried out post-deposition
72 to address this challenge have been the subject of an excellent review.³⁷ Advances in area-selective
73 CVD and ALD for certain mono-layer TMDCs on lithographically-patterned substrates have also been
74 reported.^{38,39} However, there is considerable interest in developing novel TMDC growth methods
75 capable of delivering high quality, patterned 2D-TMDC layers directly.

76 This article reviews the state-of the-art for the growth by electrodeposition of layered metal
77 chalcogenide materials for semiconductor applications, with particular emphasis on the prospects for
78 the scalable growth of ultrathin 2D TMDCs. Here, direct TMDC electrodeposition onto pre-defined
79 regions of the substrate is of particular interest. For a discussion of the electrodeposition of
80 semiconductor materials in general, the reader is directed to the reviews by Schlesinger *et al*⁴⁰ and
81 Lincot.⁴¹ A monograph on electrodeposition of a broader range of metal chalcogenides from across
82 the periodic table is also available.⁴² Among the most important considerations to deliver the precise
83 stoichiometries, structures and morphologies, are the choice of the molecular precursor(s), the
84 solvent, the nature and design of the electrode and the specific deposition parameters employed,
85 each of which will be discussed. Developments in the use of **single source precursors (SSPs) [G]**
86 (molecules or ions in which the directly bonded metal-chalcogen unit is already built-in), together with
87 emerging work on the electrochemical growth of TMDCs from the edge of nano-band electrodes, are
88 also highlighted.

89

90 **[H1] Electrodeposition**

91 Electrodeposition (also known as electroplating) is a technology that dates to the early 19th century
92 and was first used to make printing plates and to apply decorative coatings such as silver plating on
93 cutlery. Today it is often associated with large-scale engineering or decorative applications, such gold,
94 nickel or chrome plating, with many thousands of electroplating businesses operating worldwide. It is
95 widely used in printed circuit board manufacture, to grow thin films for the read heads in the
96 manufacture of hard-disc storage drives⁴³ and to deposit metals and alloys. This application makes use
97 of its ability to produce adherent, conformal coatings. Electrodeposition is also a key technology for

98 fabricating nano-scale electronics over 12-inch diameter wafers where it is the key step used to make
99 the Cu interconnects and vias that wire up the (ca. 0.13 trillion) transistors in high-performance
100 microprocessors through the Damascene process.⁴⁴

101 **[H2] Principles and criteria for electrodeposition**

102 The choices of solvent, electrolyte [G], salt and precursor for electrodeposition are governed by
103 chemical constraints and there are often trade-offs that need to be made. There are important
104 chemical factors that need to be considered when choosing the composition of the electrodeposition
105 solution and in the design of precursor compounds. An excellent introduction to electrodeposition can
106 be found in Paunovic and Schlesinger's book.⁴⁵

107 First, the choice of solvent determines the accessible potential range and is important because it can
108 act as a competitor ligand for the molecular precursor compound(s), leading to formation of additional
109 coordination species in solution.⁴⁶ The purity of the solvent is crucial since small amounts of
110 electroactive impurities can have a considerable effect.

111 Second, the choice of electrolyte has a significant effect. The electrolyte salt (C^+A^-) must not only
112 dissolve in the solvent, but also dissociate to form mobile cations (C^+) and anions (A^-) so that the
113 electrolyte solution is conducting. Its purity is again important because it is present at high (typically
114 > 0.1 M) concentration. Many electrolytes are available, and their properties vary with the choice of
115 cation and anion. For example, the choice of Cl^- as opposed to $[BF_4]^-$ or a fluorinated tetra-arylborate
116 (BAr^F) anion, can have a considerable influence because of their differences in nucleophilicity. The
117 choice of the electrolyte can also limit the potential range, since the anion or cation can undergo
118 electrochemical oxidation or reduction (for example, at positive potential $Cl^- \rightarrow \frac{1}{2}Cl_2(g) + e^-$).

119 Third, the choice of precursor is also crucial. The chosen precursor compound(s) must be both soluble
120 and stable in the electrolyte solution. Note that there can be ligand exchange, so there may be a
121 mixture of coordination species in solution (speciation). For example, for $[N^rBu_4]_2[TeCl_6]$ dissolved in
122 CH_2Cl_2 containing $[N^rBu_4]Cl$, the Te(IV) exists as a mixture of complex anions in equilibrium with the
123 Cl^- anions from dissociation of $[N^rBu_4]Cl$ in the electrolyte solution.⁴⁷ This speciation can affect
124 electrodeposition because the different complexes have different redox potentials and can have
125 different electrochemical kinetics. The redox potential of the molecular precursor is an important
126 factor – ideally it should be within the available potential range of the electrolyte solution so that
127 electrodeposition is not accompanied by considerable electrochemical decomposition of the
128 electrolyte. In general, this can be achieved through judicious choice of the ligands and the speciation
129 of the precursor.⁴⁸

130 Finally, the counter electrode [G] reaction also needs to be considered since an equal, but opposite,
131 current must be passing at the counter electrode. For aqueous solutions this can often be
132 accommodated by the evolution of oxygen gas which bubbles from the solution, but for non-aqueous
133 solutions and ionic liquids the counter electrode reaction needs more careful thought.

134 ***[H2] Electrodeposition - an alternative route to TMDCs***

135 In comparison to CVD and ALD, in which the precursor species are delivered in the vapour phase (gas
136 phase) and the material growth is driven thermally, there has been much less work using
137 electrodeposition for the growth of 2D-TMDCs. However, electrodeposition offers a distinct set of
138 variables and parameters that can be optimised to control the growth of ultrathin, highly anisotropic
139 TMDC layers. Figure 2a illustrates the typical experimental set-up for electrodeposition using a three
140 electrode system, comprising a working electrode, counter electrode and reference electrode, to
141 maintain accurate control of the applied potential, along with indicative responses from some of the
142 electrochemical experiments that are most relevant to this area of work (Figures 2b-d). Figure 2e
143 shows a typical response from a chronoamperometric electrodeposition experiment, where the
144 current is monitored as a function of time.

145 Most importantly, electrodeposition is inherently a localised (area-selective) process, providing the
146 ability to grow the TMDC directly from a conductor into or onto a particular device architecture
147 precisely where required. This capability is extremely attractive for the production of new TMDC-
148 based nano-devices, as it would eliminate the need for post-deposition etching and patterning
149 processes.

150 There have been many papers on the electrodeposition of TMDC materials from aqueous (usually
151 acidic) electrolytes often containing a different precursor to deliver each of the metal and the
152 chalcogen. However, in general, the specific molecular species (ions and/or molecules) that exist in
153 these electrolytes have not been determined and so the actual reactive chemical species in the
154 electrolyte are usually not known.^{49,50} As a result, the electrochemical processes that are observed
155 during TMDC electrodeposition are generally not thoroughly understood. Electrodeposition from
156 aqueous solution in these particular experiments also generally produces deposits that are irregular
157 and amorphous or polycrystalline. These are very suitable for (electro)catalysis, battery and super-
158 capacitor applications, which has been the motivation behind most of this work to-date.⁵¹ For
159 example, in electrocatalytic water-splitting (the conversion of water into hydrogen and oxygen gas),
160 the presence of many nanocrystalline or amorphous TMDC particles is advantageous as the catalytic
161 reactions occur at defects and the edge sites of the 2D crystallites. However, these materials do not

162 display the highly anisotropic, extended 2D structures across the dimension scale (typically from a few
163 nm² to tens of μm²) required for future electronic and optical device applications.

164 In addition, aqueous electrolytes are inherently not well-suited for achieving fine control of 2D TMDC
165 growth by electroreduction because of the generation of hydrogen gas, which dominates the
166 voltammetric response at negative potentials. This can cause bubbles to form, and gives rise to a large,
167 broad reduction wave in the voltammogram, which limits the potential window that can be used to
168 drive the deposition of the TMDC itself.

169 When considering the fabrication of nano-devices using electrodeposition, the high surface tension of
170 water can also hinder the penetration of aqueous electrolytes into high aspect-ratio structures. There
171 are two other important considerations from a chemistry perspective. Firstly, the incompatibility of
172 acidic aqueous media with many potential precursors, severely limiting the use of moisture-sensitive
173 precursors that may otherwise be suitable for TMDC electrodeposition. Secondly, the Lewis basicity
174 of water can lead to H₂O displacing one or more of the ligands present in the original precursor
175 compound. This can cause the formation of multiple different species in the electrolyte solution, each
176 of which will exhibit its own characteristic redox response. This is likely to result in more complicated
177 electrochemical responses and loss of the potential-control necessary for growth of high quality 2D
178 TMDC layers.

179 To explore 2D TMDCs for transistor and optical applications, several requirements need to be met to
180 be able to deliver materials of sufficient quality. These include the need for large-scale production of
181 single crystalline, mono-/few-layer TMDCs directly onto pre-patterned wafers, and control of the
182 number and types of defects present. Other important considerations are the precise M:E ratio in the
183 deposited material, the number of layers, and the ability to form heterostructures, since they will
184 directly affect the functional properties of the TMDCs. Compatibility of the growth process with
185 existing industrial manufacturing is also important if the process is to be adopted.

186 The high level of interest in these materials has also prompted efforts to explore alternative,
187 complementary TMDC growth methods, including electrodeposition, to promote growth in the 2D
188 plane. One reason for this is that precise control over heterostructure formation allows the
189 development of hybrid devices that, for example, integrate sensing and computation components in
190 one device,⁵² or for optoelectronic devices, where it improves both the responsivity and the response
191 time of photodetectors.⁵³

192

193

194 ***[H2] Controlling morphology and crystallinity***

195 Key considerations to achieve successful electrodeposition are the morphology and crystallinity of the
196 deposit. The choice of deposition conditions (such as potential, mass transport, temperature, and
197 concentration) will affect the morphology of the electrodeposited film and, in the case of the
198 deposition of alloys or compounds (as opposed to pure elements), the composition of the deposit.
199 The applied potential (which directly controls the energetic driving force for the deposition), and the
200 mass transport conditions (for example stirring, or more controlled mass transfer using a rotating disc
201 electrode, which replenishes the precursor concentration at the electrode) can be used to tune the
202 structure of the generated TDMC. The mass transport in solution regulates the supply of the precursor
203 molecules or ions and removal of any soluble by-products from the electrode surface. This can be
204 important if there are coupled chemical reactions that are part of the overall electrodeposition
205 process or where the ligands liberated during electrodeposition can change the local speciation at the
206 electrode surface. For commercial plating baths it is not uncommon for specific technological
207 developments that achieve the required outcomes to be developed on a trial and error basis.

208 A common approach to altering the morphology of electrodeposited films is to use additives. These
209 are molecules that are added to the electrodeposition solution, generally at low concentration, that
210 strongly adsorb on specific sites at the surface of the growing deposit and either inhibit or accelerate
211 the local rate of deposition. Two common classes of additives are **brighteners [G]** and **levellers [G]**.
212 Brighteners produce finely structured reflective deposits, whereas levellers reduce surface
213 irregularities by slowing deposition on surface protrusions. Another common approach is to use
214 pulsed deposition, in which the deposition potential is stepped between a high overpotential to favour
215 the formation of many nucleation sites, followed by a lower overpotential to grow material on the
216 nucleation sites at a slower rate. The control of electrodeposit morphology is a complex subject and
217 is beyond the scope of this review. The reader is referred to the specialist literature for more details.⁴⁰

218 ***[H2] Electrode materials and designs***

219 In principle, a wide range of conducting materials can be used as substrates (electrodes) for
220 electrodeposition. In practice, however, for fundamental electrochemical studies Pt, Au and glassy
221 carbon electrodes are readily available and are most commonly used in the laboratory because they
222 are convenient; they are robust, can be cleaned by polishing, and can be reused. For nano-electronic
223 device applications, including metal chalcogenides, metals and alloys with high melting points and low
224 reactivity that act as a diffusion barrier are preferred. This prevents migration (diffusion) of atoms or
225 ions from the electrode into the deposit causing contamination. For nanodevice applications, TiN and
226 carbon, in the form of graphene, are particularly suitable as these can be patterned using conventional
227 nanofabrication processes. In the case of micro- and nano-fabricated structures, polishing of the

228 electrode surface, which is often undertaken in electrodeposition to reduce roughness and/or remove
229 surface impurities, is impractical and other cleaning methods (plasma cleaning, electrochemical
230 cleaning, *etc.*) must be used.

231 For fundamental studies of the voltammetry, disc electrodes, formed by encasing a wire or rod of the
232 electrode material in an insulating cylinder, are typically favoured since they have a well-defined
233 surface area and can be cleaned by polishing. These can be **macroelectrodes [G]** (diameter > 0.1 mm),
234 where mass transport is dominated by **planar diffusion [G]** (Figure 2b), **microelectrodes [G]** (diameter
235 < 50 μm), where **radial diffusion [G]** dominates (Figure 2c), and rotating disc electrodes, where the
236 rotation allows calculable and well-defined forced convective mass transport (Figure 2d). Of these, the
237 use of microelectrodes more closely corresponds to the mass transport conditions for deposition on
238 microfabricated structures. The use of microelectrodes also has the advantages of steady-state
239 diffusional mass transport and reduced ***iR* drop [G]** (reducing distortions in the electrochemistry
240 caused by poor control of the electrode potential as a result of high solution resistance), making them
241 a good choice for fundamental studies of the electrochemistry of the precursor compounds.⁴¹

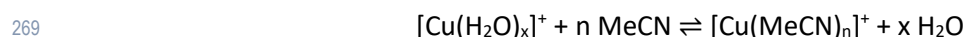
242 For device applications, electrode structures are fabricated on planar substrates (typically commercial
243 12-inch Si wafers) using a range of standard cleanroom nanofabrication techniques to deposit and
244 pattern thin (10 – 100 nm) films of conductors and dielectrics. Industrially, electrodeposition
245 subsequently happens on a full-wafer scale, though in the research environment, the wafers are
246 usually diced before electrodeposition with limited further processing afterwards (see, for example
247 Ref. 41). Aggressive scaling down to nanoelectrodes and deposits is possible as the electrode
248 resistance and necessary current for electrodeposition scale identically, keeping a constant *iR* drop
249 independent of size.⁵⁶

250 **[H1] Solvents and speciation**

251 A variety of solvents can be used for the electrodeposition of TMDCs and related layered metal
252 chalcogenides, from water to non-aqueous solvents (such as MeCN, DMF, DMSO, propylene
253 carbonate, CH_2Cl_2), to ionic liquids such as such as [bmim][BF_4] or [bmim][CF_3SO_3] (bmim = 1-butyl-3-
254 methylimidazolium),⁵⁷ and deep eutectic solvents, such as choline chloride/ethylene glycol.⁵⁸ Acidic
255 aqueous electrolytes and other protic solvents, like alcohols and glycols, are often used for
256 electroplating materials onto large area surfaces and there are many reports describing the
257 electrodeposition of various ME_2 ($\text{M} = \text{Zr}, \text{Mo}, \text{W}$; $\text{E} = \text{S}, \text{Se}, \text{Te}$) or $\text{M}'_2\text{E}_3$ ($\text{M}' = \text{Sb}, \text{Bi}$) materials from
258 acidic aqueous electrolytes. Typical metal precursors are sulfate salts, such as $\text{Zr}(\text{SO}_4)_2$,⁵⁹⁻⁶² and oxo-
259 anions, $[\text{MoO}_4]^{2-}$ ⁶³⁻⁷⁸ and $[\text{WO}_4]^{2-}$.⁷⁹⁻⁸² For the $\text{M}'_2\text{E}_3$ materials, metal halides such as $\text{M}'\text{Cl}_3$,⁸³⁻⁸⁷ or oxo-
260 halides, $\text{M}'\text{OCl}$,⁸⁸⁻⁹⁰ are often used. Typical chalcogen sources used in this area of work are Na_2S ,
261 $[\text{S}_2\text{O}_3]^{2-}$, thiourea, SeO_2 , $[\text{SeO}_3]^{2-}$, TeO_2 or $[\text{TeO}_3]^{2-}$. The majority of MoS_2 and WS_2 materials produced

262 by electrodeposition from aqueous solution have been for use in electrocatalytic water-splitting to
263 generate hydrogen. For these processes the catalytic reactions take place on the exposed edges of the
264 TMDC rather than on the vdW surfaces, so the rough, nanocrystalline or amorphous deposits, with
265 many exposed edges, that are typically produced from these electrolyte baths are advantageous.

266 Turning to non-aqueous solvents, MeCN is one of the most commonly used non-aqueous solvents for
267 electrochemical studies. However, it is important to be aware that MeCN can also act as a ligand,
268 changing the speciation of the initial precursor, for example in:⁹¹



270 Thus, it is important to consider the effect of the choice of solvent on the speciation of the precursor.
271 Room temperature ionic liquids (RTILs) and deep eutectic solvents have superseded water for the
272 electrodeposition of some chalcogenide materials. Examples include, TiS_2 (from TiCl_4 and $\text{Na}_2[\text{S}_2\text{O}_3]$ in
273 a choline chloride/urea eutectic),⁹² and polycrystalline MoS_2 ⁹³ and Bi_2E_3 ⁹⁴ from RTILs. These solvents
274 can have wide potential windows,^{95,96} the option to access high electrodeposition temperatures (due
275 to their high boiling points) and reduce the problems associated with H_2 evolution that occur during
276 the deposition process from water and alcohols. However, ionic liquids can be difficult to purify
277 sufficiently for use in electrodeposition and, like water, also exhibit relatively high surface tensions.⁹⁷

278 When thinking about the choice of solvent and effects on speciation, it is useful to classify different
279 solvents based on Kamlet and Taft's π^* , α and β parameters, where π^* , α and β describe the polarity,
280 **Lewis acidity [G]** and **Lewis basicity [G]**, respectively (Table 1).⁹⁸ Suitable solvents, should be polar (π^*
281 ≥ 0.55), aprotic ($\alpha \leq 0.2$), and weakly coordinating ($\beta \leq 0.2$).⁹⁹ This ensures that the electrolyte salt will
282 dissociate sufficiently to make the solution conducting and that the solvent will not coordinate
283 strongly with the precursor. The Taft solvent descriptors show that the commonly used non-aqueous
284 solvents, such as DMSO, ethylene glycol and ionic liquids, are more Lewis basic than solvents such as
285 CH_2Cl_2 .

286

287 The so-called 'weakly-coordinating solvents',⁹⁹ such as CH₂Cl₂, generally have low donor-power. This
288 reduces their tendency to compete as a ligand towards the dissolved precursors, leading to fewer
289 different species in the electrolyte. They can be beneficial for the deposition of TMDCs, where the
290 semiconducting behaviour is determined by the precise stoichiometry, structure, defect concentration
291 and morphology of the material. When considering these alternative (aprotic) solvents, the
292 electrochemical window of the solvent is a key factor, since this determines the potential range within
293 which electrodeposition can be performed cleanly without introducing impurities from solvent
294 degradation. The solvent donor properties also determine its compatibility with certain precursor
295 compounds. MeCN, CH₂Cl₂ and supercritical CH₂F₂ have been used to facilitate the electrodeposition
296 of various *p*-block elements, for example, elemental Te,¹⁰⁰ (sulfur-rich) WS₂ from [NH₄]₂[WS₄],¹⁰¹
297 mono- and few-layer TMDCs from SSPs, and ternary GeSbTe alloys from electrolytes containing
298 multiple precursors.^{102,103}

299 **[H1] Molecular precursors**

300 To identify suitable molecular precursors for the electrodeposition of metal chalcogenides from
301 weakly coordinating solvents, several criteria need to be met. The precursor needs to be sufficiently
302 soluble in the low polarity solvents and dissociation of precursor salts should occur to produce well-
303 defined ions. Additionally, the reduction potentials for the precursor molecules/ions should be well-
304 defined and accessible within the potential limits of the solvent electrolyte used. These will be
305 dependent on the particular metal ion in the precursor, its oxidation state and the co-ligands present.
306 The nature and fate of the ions and ligands that are liberated during the deposition process must also
307 be considered to avoid undesirable chemical reactions in the electrolyte or precipitation of impurities
308 during the deposition process.

309 This can be illustrated by considering the electrodeposition of elemental tellurium from
310 [NⁿBu₄]₂[TeCl₆] salt in CH₂Cl₂ (Figure 3). The [NⁿBu₄]⁺ cation aids solubility of the salt in the low polarity
311 CH₂Cl₂ solvent, and is not electrochemically active within the normal potential window of the solvent.
312 Hence, this system has a cathodic potential limit that is suitable for observing the electroreduction of
313 the [TeCl₆]²⁻ anion. [NⁿBu₄]⁺ is also the same cation that is present in the [NⁿBu₄]Cl supporting
314 electrolyte. As the elemental tellurium is deposited from the [TeCl₆]²⁻ precursor, Cl⁻ anions are
315 liberated and released into the solution; these are the same as the anion of the supporting electrolyte,
316 therefore the ions present in the electrolyte do not change during the process.¹⁰⁴ It is important to
317 note that the higher concentration of Cl⁻ at the electrode surface can alter the local speciation (e.g. in
318 the Te case at low Cl⁻ electrolyte concentration) and this may change the chemistry of the
319 electrodeposition reaction. This general strategy has been used successfully for the electrodeposition

320 of a wide range of *p*-block elements from CH₂Cl₂-based electrolytes, including Se, Te, Sb, Bi, Ga, In,¹⁰⁴
321 Sn,¹⁰⁵ and Pb.¹⁰⁶

322 In some cases, different oxidation states of the *p*-block ion in the halometallate salt precursors can
323 also be accessed by varying the synthesis procedure. For example, while Te(IV) is present in [TeCl₆]²⁻,
324 Te(II) can be incorporated in the form of [TeI₄]²⁻.^{47,107} Similarly, Ge(IV) can be incorporated in the form
325 of [GeCl₅]⁻ or [GeCl₆]²⁻, whereas the [GeX₃]⁻ anions (X = Cl, Br, I) contain Ge(II).¹⁰⁸ The choice of
326 oxidation state and the nature of the halide ion (X⁻) in the precursors also allow the electrochemical
327 reduction potentials of the *p*-block halide ions to be tuned. This is particularly important when
328 combinations of these salts are required to deposit a binary or ternary chalcogenide material.

329 For each of the *p*-block halometallate precursors above, when performing electroreduction to deposit
330 the elemental form, the transfer of multiple electrons is required. For example, reduction of Te(IV) to
331 Te(0) involves a four electron reduction. While the literature often implies that this occurs by
332 *simultaneous* multi-electron reduction processes, in practice this is implausible based on Marcus
333 theory.¹⁰⁹ The electroreduction of Te(IV) to Te(0) has been investigated in some detail by using a
334 combination of electrochemical experiments in CH₂Cl₂, together with density functional theory
335 calculations. This has led to a proposed catalytic process that involves the interaction of a
336 coordinatively unsaturated Lewis acidic species ([TeCl₅]⁻), produced via the equilibrium shown in
337 Figure 3a, with the filled *p*-type orbitals projecting out from the surface of the growing Lewis basic
338 Te(0) deposit (Figure 3b). It is proposed that this is followed by a sequence of one-electron transfer
339 processes to cause 'stepwise reduction' to elemental tellurium, accompanied by liberation of further
340 chloride ions from the tellurium.⁴⁷

341 Two distinct strategies for molecular precursor development for the electrodeposition of metal
342 chalcogenide materials from weakly coordinating solvents have been established. The first, and more
343 commonly used to-date, uses 'multi-source precursors'. In this case, each element required for the
344 target TMDC is delivered from a separate precursor compound. In the second approach both the metal
345 and the chalcogen are bonded together and contained in a single molecular entity – 'single source
346 precursors' (SSPs).

347 **[H2] Electrodeposition using multi-source precursors**

348 Electrodeposition of binary metal chalcogenides from multi-source precursors requires a combination
349 of two different precursor compounds that form a chemically stable electrolyte, hence the
350 compatibility of the individual salts in the solvent must also be considered. It has been found that
351 combining the Bi(III) salt, [NⁿBu₄][BiCl₄], with the Te(IV) salt, [NⁿBu₄]₂[TeCl₆], in CH₂Cl₂ containing
352 [NⁿBu₄]Cl supporting electrolyte forms a chemically stable electrolyte that allows the growth of the

353 target Bi₂Te₃ thin film semiconductor under electrochemical control.¹ In contrast, combining the Ge(II)
354 salt, [NⁿBu₄][GeCl₃], with the same Te(IV) salt, [NⁿBu₄]₂[TeCl₆], in CH₂Cl₂, gives an unstable electrolyte
355 that undergoes a spontaneous chemical reaction, precipitating elemental Te. This is most likely caused
356 by the chemical oxidation of the Ge(II) (to Ge(IV)) by the Te(IV), which is itself reduced to Te(0).
357 However, swapping to the Ge(IV) precursor, [NⁿBu₄][GeCl₅] (or a [GeCl₆]²⁻ salt),^{102,103} in combination
358 with [TeCl₆]²⁻ gives a stable multi-source electrolyte²⁻ that can be used to electrodeposit germanium
359 telluride under electrochemical control.

360 This approach has also proven to be remarkably effective for the deposition of various ternary alloys
361 of GeSbTe onto TiN electrodes, which, although not a TMDC, is an important material for solid state
362 memory applications, using a multi-source electrolyte containing [GeCl₅]⁻, [SbCl₄]⁻ and [TeCl₆]²⁻ (Figure
363 4a).^{102,103} In this case, the cyclic voltammetry shows distinct reduction waves for each of the three
364 chlorometallate anions (Figure 4b). It is also possible to tune the composition of the alloy by adjusting
365 both the relative ratios of the precursor salts in the electrolyte and by altering the reduction potential
366 for the electrodeposition, allowing a range of alloy compositions to be accessed using this suite of
367 precursors. This strategy has also been used for the deposition of functional GeSbTe alloys into a range
368 of micro- and nano-patterned electrodes, by exploiting the area-selectivity inherent to
369 electrodeposition. These materials were then investigated for application in solid state memory where
370 their growth as thin films onto specific areas of pre-patterned arrays within geometrically constrained
371 3D nano- and micro-structures are advantageous for fast switching at low power and with high
372 endurance.^{111,112}

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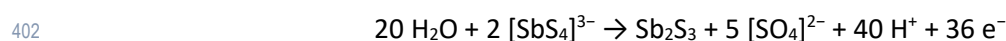
375 **[H2] Electrodeposition using single source precursors**

376 Since SSPs contain pre-formed M=E bonds, they can result in better-defined solution speciation in the
377 electrolyte, as well as a simpler voltametric response, compared to multi-source precursors. This can
378 be beneficial for the controlled growth of mono- and few-layer TMDCs, where precise control of the
379 deposition conditions is advantageous.

380 Ammonium (NH₄⁺) salts of [MoS₄]²⁻ and [WS₄]²⁻ are commercially available and have been the subject
381 of intense research interest for the electrodeposition of MoS₂¹¹³⁻¹³³ and WS₂¹³⁴⁻¹³⁶ onto various
382 electrode arrangements from aqueous electrolytes. The [NH₄]⁺ cations (or H₂O in aqueous
383 electrodeposition) serve as the proton source to remove the excess sulfur (as H₂S). Typically, the as-
384 deposited metal sulfides produced from the metal tetrathiolate precursors in aqueous electrolytes
385 have stoichiometries considerably higher than the 1:2 ratio required for the deposition of the metal

386 disulfide and these can be converted to polycrystalline ME₂ by high temperature annealing. They have
387 been produced by electrodeposition for a range of applications, including,
388 electrocatalysis,^{113,114,116,118,119,127,130} solar cells,^{120,122} battery materials,¹²³ supercapacitors¹²⁹ and
389 sensing.^{117,124} However, these conditions generally produce deposits that are rough and irregular and
390 therefore not well-suited for electronic or optical applications. [MoE₄]²⁻ (E = S, Se) have also been used
391 as SSPs to deposit dense amorphous nanoparticles of MoS₂ and MoSe₂ from an ionic liquid for
392 hydrogen evolution catalysis.¹³⁷ The low costs associated with electrodeposition, coupled with its
393 scalability, are particularly attractive for these applications.

394 The suitability of SSPs based on other [MS₄]^{x-} anions (Figure 5a) is of interest to explore the versatility
395 of this approach for electrodepositing other metal sulfide materials. For example, an aqueous
396 [NH₄][ReS₄] electrolyte has been implemented for the electrodeposition of ReS₂ onto 2D- and 3D-
397 printed carbon electrodes for the photo-/electrochemical oxidation of water.¹³⁸ All of the [ME₄]^{x-}
398 precursors discussed so far produce the target metal chalcogenide under cathodic deposition (*via*
399 electroreduction). In contrast, it has been shown that Schlippes salt, Na₃[SbS₄]·9H₂O, can be used as a
400 SSP in aqueous alkaline solution to produce Sb₂S₃ films by anodic electrodeposition, according to the
401 equation:



403 In this unusual case, the reduction of the Sb⁵⁺ to Sb³⁺ is accompanied by oxidation of the liberated
404 sulfide to sulfate. Interest in Sb₂S₃ thin films arises from their resistive memory switching behaviour.¹³⁹
405 As discussed, weakly coordinating solvents such as CH₂Cl₂ offers some advantages for TMDC
406 electrodeposition compared to using water. However, the commercially available [NH₄]₂[MS₄] (M =
407 Mo, W) salts are poorly soluble in CH₂Cl₂. Therefore, it is necessary to change the [NH₄]⁺ cation to an
408 organic ammonium cation, such as [NⁿBu₄]⁺. The [NⁿBu₄]₂[MoS₄] salt exhibits good solubility in CH₂Cl₂,
409 and studies on their suitability as SSPs have been very promising. The deposition of MS₂ from these
410 sulfur-rich [MS₄]²⁻ anions require the excess sulfur to be removed as H₂E. For the [NⁿBu₄]₂[MoS₄]
411 precursor in CH₂Cl₂, this can be achieved by the addition of a small amount of an organic proton
412 source, such as [NMe₃H]⁺. This enables the cathodic deposition of amorphous MoS_{2,3} thin films onto
413 TiN electrodes, which are converted to crystalline 2D MoS₂ by annealing.¹⁴⁰ However, the breakdown
414 of the proton source also occurs in a similar region to the [MoS₄]²⁻ reduction and dominates features
415 in the voltammetry, restricting the usable potential window in CH₂Cl₂ electrolytes. The reduction
416 process for the analogous [NⁿBu₄]₂[WS₄] salt is completely masked by the peak associated with the
417 breakdown of the [NMe₃H]⁺ cation in the cyclic voltammogram, therefore WS₂ has not been obtained
418 from this precursor.¹⁴¹ Alternative SSPs for WS₂ are not available commercially.

419 Although they are not available commercially, the corresponding tetraselenometallate anions of Mo
420 and W, $[\text{MSe}_4]^{2-}$, can be synthesised using established literature methods.^{142,143} The $[\text{N}^n\text{Bu}_4]_2[\text{MSe}_4]$
421 (M = Mo, W) salts also have good solubility in weakly coordinating solvents such as CH_2Cl_2 . Analogy
422 with the $[\text{MoS}_4]^{2-}$ ion, which is an effective SSP for MoS_2 electrodeposition, could suggest that the
423 $[\text{MoSe}_4]^{2-}$ ion may be suitable as a SSP for the electrodeposition of 2D-layered MoSe_2 films. However,
424 to achieve this, it will be necessary to identify an effective way to remove the excess selenium.

425 The need for a proton source to exploit these $[\text{ME}_4]^{2-}$ salts as SSPs has stimulated efforts to synthesise
426 alternative precursors that contain the specific 1:2 metal:chalcogen ratio required for the target TMDC
427 semiconductor, since this removes the need for the proton source and simplifies the electrochemistry.
428 The tungsten(VI) sulfide chloride, WSCl_4 , can be converted to the *cis*- $[\text{WS}_2\text{Cl}_4]^{2-}$ anion (Figure 5b),
429 which was originally isolated as its $[\text{PPh}_4]^+$ salt,¹⁴⁴ and later as its $[\text{NEt}_4]^+$ salt for electrochemical
430 studies.¹⁴¹ Thin films of WS_2 have been obtained by cathodic electrodeposition onto a TiN electrode,
431 and further refinement of the experimental procedures allow 2D mono- and few-layer WS_2 growth
432 from this tailored SSP. However, the corresponding tungsten selenide chloride salt, $[\text{NEt}_4]_2[\text{WSe}_2\text{Cl}_4]$,
433 has not been isolated from $[\text{WSeCl}_4]$.¹⁴⁵ This is probably because the W=Se bonds are weaker than
434 W=S bonds and therefore less stable. However, cathodic electrodeposition using the neutral $[\text{WSeCl}_4]$
435 as the SSP (Figure 5b), in MeCN with NEt_4Cl supporting electrolyte, produces very thin and smooth
436 WSe_2 films.¹⁴⁶ Despite the 1:1 W:Se ratio in the precursor, production of the WSe_2 films does not
437 require the addition of any further selenium source. It is proposed, therefore, that the deposition also
438 involves Se atom transfer, according to the reaction:



440 In the case of TMDC growth, the ability to deposit smooth, few- and mono-layer films is critical to
441 unlock their electrical and optical properties. While one way of achieving ultra-thin TMDCs in
442 electrodeposition is by controlling the deposition parameters, such as applied potential, time or
443 charge passed, an alternative route to achieve this is by electropolishing of deposited TMDCs, through
444 a top-down approach. Here, bulk TMDC materials could be thinned down to monolayers by
445 electrochemically ablating the top layers in an acidic LiCl solution.¹⁴⁷ The electropolishing relies on the
446 difference in activity of the edge sites and the relatively inert basal planes in the TMDCs, where the
447 corrosion of materials begins at the edges of the multilayer flakes and gradually progresses towards
448 the centre. Similar electropolishing strategies could be employed for electrodeposited TMDC films
449 where the growth results in bulk multi-layered thin films. This technique, combined with
450 electrodeposition, offers the prospect of an all-electrochemical pathway to achieve monolayer
451 TMDCs.

452 [H1] 2D TMDC growth onto a conductor

453 SSPs compatible with non-aqueous, weakly-coordinating solvents tend to result in better-defined
454 solution speciation, and, assuming that the deposition potential of the SSP is within the available
455 potential window, allow TMDC films with well-controlled thicknesses to be electrodeposited onto a
456 variety of electrode substrates. Electrodeposition, being an area-selective deposition method, offers
457 growth control at the molecular scale by modulating the amount of charge passed during the
458 deposition process. One of the challenges for ultra-thin (sub-5 nm) TMDC films is the choice of
459 substrate. Since electrodeposition generally produces conformal coatings of the target material over
460 electrically-defined surface features, classical metal or glassy carbon electrodes are not ideal as the
461 variation in their surface roughness is large compared to the expected thickness of 2D TMDC films.
462 This affects the film's morphology and layer-ordering. Monolayer graphene can be considered as an
463 'ideal' electrode substrate for TMDC growth as it is an atomically thin and extremely flat 2D conductor,
464 therefore electrodeposition can occur on graphene without surface roughness issues.¹⁴⁸
465 Electrodepositing the TMDCs on directly on top of graphene can also be used to produce 2D TMDC on
466 graphene heterostructures. By optimization of the deposition parameters, few-layer MoS₂/graphene
467 heterostructures have been produced from the [NⁿBu₄]₂[MoS₄] precursor in dichloromethane.¹⁴⁹ This
468 is a good example to demonstrate the nanoscale control that is possible using electrochemical
469 techniques to produce ultra-thin TMDC films and heterostructures. Figure 6a illustrates a graphene
470 electrode structure fabricated using the process in Figure 6b and implemented for ultra-thin TMDC
471 growth using SSPs in CH₂Cl₂ electrolytes.¹⁴⁹ Further work has focussed on deposition of monolayer WS₂
472 on graphene. This was selected because the electrochemistry of the [NEt₄]₂[WS₂Cl₄] precursor salt (1:2
473 W:S stoichiometry) is less complicated compared to the 1:4 Mo:S ratio in the [NⁿBu₄]₂[MoS₄]
474 precursor. In the latter, the interference of the proton source (Me₃NHCl) is unavoidable. By controlling
475 the time duration of the deposition, it has been possible to electrodeposit WS₂ monolayers onto
476 patterned graphene electrodes, as illustrated in the transmission electron microscopy (TEM) image in
477 Figure 6c.¹⁵⁰

478 In addition to graphene, in principle, a semiconducting TMDC itself can be used as a substrate for
479 electrodepositing a different TMDC material on top, to achieve vdW heterostructures.
480 Electrodeposition offers a unique advantage here, as the TMDC heterostructures can be
481 electrochemically deposited by simply switching the electrolyte solution. If the material quality is
482 sufficiently high, this 2D heterostructure electrodeposition method could be extended to produce *p*-
483 *n* junctions. An interesting target would be to deposit WSe₂ (*p*-type) on top of MoS₂ (*n*-type).

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[H1] 2D TMDC growth over an insulator

As explained, traditionally, electrodeposition has been used to grow materials on top of conducting surfaces (electrodes). However, in the case of TMDCs, this prevents the direct electrical characterisation of the semiconductor material that is deposited, because the high conductivity of the electrode will dominate the electrical response. Moreover, depositing a semiconducting TMDC film on a conductor also limits the film's applications in electrical devices such as transistors. For these reasons, film transfer is required to enable electrical measurements of the electrodeposited TMDC films. Therefore, novel electrochemical techniques that enable the deposition of 2D materials onto insulating surfaces need to be developed.

One possible approach takes advantage of the strong anisotropy resulting from their 2D-layered structures, which helps to propagate the in-plane growth. This has been exploited to drive the TMDC growth over an insulating substrate (e.g. SiO_2) as illustrated in Figure 7. It has been achieved by constructing microelectrode structures, where the electrochemical growth starts at the *edge* of very thin **nano-band electrodes [G]** and progresses out from the electrode and over the insulator, as illustrated in the schematic in Figure 7a. Each individual electrode can be electrically-addressed separately, allowing deposition of one material (TMDC-1) from the left nano-band TiN electrode, and, if desired, a different material (TMDC-2) from the right side, as illustrated in Figures 7b-d. The clean-room processes required to fabricate these unusual electrode structures are shown in Figure 7e.¹⁵¹ The rationale for this design is that since the tops of the electrode surfaces are covered by an insulator (SiO_2), only the extremely thin edges of the TiN nano-band electrodes (thickness sub-100 nm) are exposed to the electrolyte. Therefore, after nucleation onto the electrode edges under electrochemical control, growth progresses out over the insulating SiO_2 surfaces. This is promoted by the inherent 2D anisotropy of the TMDC. Using this nano-band electrode structure it has been shown that in-plane 2D growth of the MoS_2 across a 7 μm wide SiO_2 channel is around 20 times faster than the rate of inter-layer growth.¹⁵¹ Figure 7f shows a TEM image of a region of tri-layer MoS_2 (after annealing) deposited in this way (i.e. where TMDC-1 = TMDC-2 = MoS_2). The amount of deposited material, and thereby the extent of 2D growth can be tuned by varying the precursor concentration, the duration of deposition or the quantity of charge passed during the deposition.

519 Using this nano-band electrode structure to drive the electrodeposition of the TMDC over the
520 insulator therefore facilitates the deposition of ultrathin 2D TMDC films onto ‘device-ready’ substrates
521 (suitable for developing 2D transistors). An additional advantage of the electrode configuration is that
522 it enables the direct characterisation of the electrical properties of the resulting films, without film
523 transfer. The current-voltage (i - V) measurements of the resulting MoS₂ films confirm the quality of
524 the deposited MoS₂, which were later used to demonstrate photodetector devices.¹⁵¹ Similar nano-
525 band electrode structures have also been employed for the electrodeposition of WSe₂ from [WSeCl₄]
526 in MeCN,¹⁴⁶ resulting in smooth 2D WSe₂ thin films over the SiO₂ microchannels. This suggests that
527 this is a versatile approach for the production of a range of ultra-thin TMDC semiconductors.

528 Nano-band electrodes could also provide a method for stacking 2D heterostructures, where the
529 heterostructure can, for example, form a p - n junction, by growing different TMDCs from the left and
530 right electrodes until the films overlap (Figure 7a). This can be achieved because each individual
531 electrode shown in Figure 7b can be controlled separately so that the electrodeposition could be
532 performed either simultaneously from both sides of the nano-band electrodes, or only from one side.

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540 [H1] Conclusion and Outlook

541 Most of the existing literature on the electrodeposition of TMDCs has been focused on delivering
542 TMDC materials suitable for (electro)catalytic and energy (solar cells, batteries, supercapacitors)
543 applications, for which nanocrystalline or amorphous materials are ideal. Also, the majority of reports
544 use aqueous electrolytes containing multi-source precursors to deliver the target TMDC. However, it
545 has been shown that by using SSPs containing pre-formed metal-chalcogen bonds, in combination
546 with weakly coordinating solvents, where the solution speciation of the precursor is well-defined,
547 allows more precise control of the deposition potential and the material growth. Therefore, the
548 controlled electrochemical growth of ultrathin 2D-layered TMDCs is an emerging area of research with
549 good prospects for the scalable production of TMDCs for electrical and optical applications. Notably,
550 compared to CVD, where there has been a huge amount of work done, electrodeposition of 2D TMDCs
551 is still at the early stages of development, but we anticipate a considerable increase in research

552 interest in this area in the coming years. A key remaining challenge is that the range of molecular SSPs
553 with the necessary characteristics to specifically promote in-plane 2D TMDC growth is currently
554 limited. Therefore, new developments in inorganic synthesis are necessary to produce novel SSPs to
555 improve control of the TMDC material quality further and to extend the range of TMDCs that can be
556 electrodeposited. This will allow tuning of the electrical and optical properties for particular target
557 applications. For example, smooth 2D NbS₂ and NbSe₂ films are interesting targets due to their
558 intriguing magnetic properties, while transition metal ditellurides from SSPs are yet to be realised. A
559 recent review of transition metal chalcogenide halide chemistry may offer routes for other possible
560 SSPs.¹⁵² The precursor choice may also enable band-gap tuning.

561 Realising the potential of this emerging area requires further optimization of both the molecular
562 precursors to deliver the ME₂ layers and the electrodeposition process and conditions to form
563 uniform, high quality, single crystalline 2D-layered TMDCs, without the need to anneal post-
564 deposition. This will require fundamental studies of the deposition mechanisms involved, including
565 the electrolyte solution speciation, the electrolyte-electrode interfaces, and the electrochemically-
566 driven deposition mechanisms. Hence, this is the second area where much new research is needed,
567 through a combined approach bringing together experimental work (precursor synthesis and
568 electrochemistry) and computational studies. Specifically, current computational work on
569 electrocatalytic H₂ evolution from TMDCs needs to be extended to DFT calculations of the precursor
570 solutions. This can then be combined with calculations on electrolyte/electrode interactions and the
571 individual deposition steps to provide further mechanistic insights. Performing the electrodeposition
572 at elevated temperatures may also increase the TMDC crystallinity because it increases the mobility
573 of intermediates on the growing TMDC surface and the rates of associated chemical reactions such as
574 ligand exchange or dissociation. To achieve this, other possible solvents with suitable solvent
575 parameters and higher boiling points could be employed.¹⁵³

576 Optimisation of the **anisotropic (in-plane) growth [G]** may be achieved by looking for molecular
577 additives that adsorb onto the chalcogenide surface of the growing TMDC inhibiting multilayer growth
578 in favour of monolayer growth. In the case of 2D TMDC growth over an insulator, the use of an
579 insulating layer of hexagonal boron nitride matching the TMDC hexagonal structure may be beneficial.
580 Electrochemical polishing also affords a possible way to thin electrochemically deposited multi-layer
581 TMDCs down to mono- or few-layer samples.¹⁴⁷

582 To electrodeposit 2D materials with the electronic and optical characteristics necessary for novel
583 devices it will be important to find ways to control the doping levels so that *n*-type and *p*-type
584 materials can be produced. This may be possible through the addition of very small amounts of a

585 chalcogen source to the electrolyte solution. Controlling the nucleation and growth will also be very
586 important for producing high quality ohmic contacts.

587 In principle, electrodeposition can also provide sufficiently precise control for monolayer-by-
588 monolayer growth of TMDC vertical heterostructures with sharp interfaces by switching the
589 electrolyte solution, similar to the electrochemical atomic layer deposition (EALD) method reported
590 by Stickney and co-workers for germanium antimony telluride films,¹⁵⁴ or by the Schwarzacher group
591 for ultrathin layer-by-layer growth of metallic multilayers for magnetic materials.^{155,156} These provide
592 interesting lines of inquiry for exploiting electrodeposition towards future TMDC-based
593 nanoelectronic and photonic devices. Increasing understanding of how the precursor chemistry
594 influences the deposition process will be critical for all of these.

595 Looking forward, as the molecular precursor chemistry evolves, the ability to achieve a controlled
596 compositional gradient or a modulated composition within a single TMDC monolayer may be possible.
597 This may be achieved by exploiting the 2D growth from a nano-band electrode design and adjusting
598 the electrochemical potential during monolayer growth. For example, it may be possible to vary the
599 composition of $\text{MoS}_{2-x}\text{Se}_x$ within a single monolayer. This might be achieved by combining two SSPs
600 with different redox potentials, one for monolayer MoS_2 electrodeposition the other for MoSe_2
601 growth, in the same solution at appropriate concentrations Then, by altering the potential and/or
602 solution composition during the deposition process, drive the growth of one material or the other.
603 Electrodeposition is uniquely suited for this because one precursor solution can be swapped to a
604 different one very easily.

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608 **Author contributions**

609 P.N.B. and G.R. conceived the idea and drafted the proposal. P.N.B., R.H., S.T. and G.R. wrote most of
610 the content. Y.J.N., C.H.D.G., R.H., V.K.G. and S.T. prepared the graphic concepts. All of the authors
611 edited and revised the manuscript.

612 **Competing interests**

613 The authors declare no competing interests.

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- 1006

1007 **Tables:**

1008 **Table 1.** The Taft solvent descriptors for some commonly used electrochemical solvents, together with
1009 those for the weakly coordinating CH₂Cl₂ (π^* , α and β describe the polarity, Lewis acidity and Lewis
1010 basicity, respectively).^{98,99} Suitable solvents typically have $\pi^* \geq 0.55$, $\alpha \leq 0.2$, and $\beta \leq 0.2$.

Solvent	π^*	α	β
MeCN	0.75	0.19	0.4
DMSO	1.00	0	0.76
Ethylene glycol	0.92	0.90	0.52
CH ₂ Cl ₂	0.82	0.13	0.01

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1014 **Figure captions**

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1016 **Figure 1:** Crystal structure of a 2D layered transition metal dichalcogenide (TMDC). a) an edge-view of
1017 the structure in a tri-layer with the layer dimensions; b) the octahedral and trigonal prismatic stacking
1018 arrangements present in different TMDC polytypes (blue = metal; green = chalcogen).

1019

1020 **Figure 2** Schematic showing a typical three-electrode electrochemical cell set-up for
1021 electrodeposition. (a) the three-electrode set-up showing the potentiostat that controls the potential
1022 between the working electrode (WE) and the reference electrode (RE) while recording the current
1023 that flows between the WE and counter electrode (CE). The RE acts as a fixed, reproducible, point
1024 against which to apply, or measure, the potential at the working electrode. This allows precise control
1025 over the driving force for electrodeposition. The three-electrode system can be used to carry out
1026 different experiments, including (b) macroelectrode cyclic voltammetry, (c) microelectrode
1027 voltammetry, and (d) rotating disc voltammetry. In all three techniques the potential of the working
1028 electrode is scanned back and forth at a constant rate and the current recorded. This enables the study
1029 and characterisation of the electrodeposition chemistry, the electrode reactions of the precursor, and
1030 the different processes (electron transfer, mass transfer, coupled solution chemical reactions, surface
1031 and adsorption processes, *etc.*) involved (see Ref. 54 for details). Negative currents in (b), (c) and (d)
1032 correspond to the deposition of material on the working electrode by reduction of the precursor in
1033 solution. Positive currents, on the return scan to positive potentials, correspond to stripping
1034 (oxidation) of the deposited material from the working electrode surface. The three-electrode system
1035 can also be used to follow the electrodeposition current as a function of time (e). The amount of
1036 material deposited on the working electrode can be controlled, or monitored, by following the total
1037 charge passed and using Faraday's law of electrolysis. (The plotted curves (b to e) are taken from

1038 experimental results for deposition of Sb from $[\text{SbCl}_4]^-$ in CH_2Cl_2 containing $[\text{N}^n\text{Bu}_4]\text{Cl}$ electrolyte in Ref.
1039 55).

1040 **Figure 3** The molecular species involved in the deposition of elemental tellurium from reduction of
1041 $[\text{TeCl}_6]^{2-}$. (a) process involved in the reversible dissociation of Cl^- (green spheres) from the $[\text{TeCl}_6]^{2-}$
1042 precursor in CH_2Cl_2 , to give the Lewis acidic $[\text{TeCl}_5]^-$ anion with a vacant coordination site (grey orbital
1043 lobe); (b) a schematic showing a $[\text{TeCl}_5]^-$ anion bonding to the Lewis basic electrodeposited Te^0 surface
1044 (orange spheres = Te) *via* interaction with a *p*-type orbital orthogonal to the growing surface. Redrawn
1045 from Ref. 47.

1046

1047 **Figure 4** Illustrating a multi-source precursor approach for the electrodeposition of ternary
1048 germanium antimony telluride alloys. (a) the structures of the three precursor anions, $[\text{GeCl}_5]^-$, $[\text{SbCl}_4]^-$
1049 and $[\text{TeCl}_6]^{2-}$; (b) a cyclic voltammogram (CV) recorded from the electrolyte containing these three
1050 chlorometallate ions in CH_2Cl_2 solution and containing $[\text{N}^n\text{Bu}_4]\text{Cl}$ supporting electrolyte – from Ref.
1051 102. The peaks corresponding to the reduction processes for each of the three reagents are labelled.

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1053 **Figure 5** Examples of single source precursors (SSPs) used for 2D-TMDC electrodeposition. (a) the
1054 $[\text{ME}_4]^{x-}$ anions; (b) the preparation methods for $[\text{WECl}_4]$ (E = S or Se) and the $[\text{WS}_2\text{Cl}_4]^{2-}$ anion.

1055 **Figure 6** Illustration of 2D- TMDC electrodeposition over a conductor (electrode). (a) Schematic
1056 showing the growth of a TMDC 2D layer onto a graphene electrode; (b) the fabrication process used
1057 to produce the microelectrodes; (c) transmission electron microscopy (TEM) image of a WS_2
1058 monolayer deposited onto graphene using the electrode structure in (a) – from Ref. 150.

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1061 **Figure 7** Schematic showing anisotropic growth of 2D-TMDCs from the edges of nano-band electrodes
1062 over an insulator (SiO_2). (a) concept diagram showing the 2D layer growing only from the exposed
1063 edges of the TiN nano-band electrode; (b) a TEM image showing an electrodeposited MoS_2 tri-layer
1064 grown using the electrode structure in (c), where MoS_2 is grown from the TiN band electrodes on both
1065 the left (TMDC-1) and right (TMDC-2); (c) illustration of the fabrication process steps (i) to (v) for the
1066 nano-band electrodes; (d) The design principle of a chip where micro-gap nano-band electrodes can
1067 enable 2D TMDC electrodeposition over an insulator; (e) and (f) show low and high magnification
1068 microscope images of the micro-gap electrode arrays with TMDCs (blue) grown between the
1069 electrodes. Redrawn from Ref. 151.

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1071

1072 Glossary

1073 area-selective growth materials growth only on specific regions of a pre-patterned substrate

1074	anisotropic growth	growth strongly favoured in one or two specific direction(s); in the case of
1075		TMDCs, this is typically from the edges of the growing layer (to produce a
1076		2D sheet)
1077	microelectrodes	an electrode with diameter < 50 μm
1078	macroelectrodes	an electrode with diameter > 0.1 mm
1079	SSP	single source precursor; a compound that can be used for depositing the target TMDC
1080		and containing pre-formed metal-chalcogen bonds
1081	electrolyte	the solution used for the electrochemical experiment, usually comprising the solvent,
1082		precursor(s) and a redox inactive cation-anion salt that dissociates in the solvent to
1083		form ions that carry the charge
1084	nano-band electrode	an electrode structure where the conducting surface is in the form of a line
1085		< 100 nm deep, typically fabricated on a silicon substrate
1086	brightener	a chemical used in electrodeposition to increase the optical brightness of the deposited
1087		material
1088	leveller	a chemical used in electrodeposition to increase the uniformity of the deposited
1089		material
1090	counter electrode	the electrode used to complete the circuit in the electrochemical cell. It has
1091		to pass an equal but opposite current from that at the working electrode
1092	planar diffusion	diffusion in 1D to/from the electrode surface
1093	radial diffusion	diffusion in 2D or 3D to/from the electrode surface
1094	<i>iR</i> drop	difference between the applied potential and the potential at the working
1095		electrode due to passage of current through solution, or other
1096		uncompensated resistance.

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1101 **Short summary**

1102 Electrochemical methods to grow 2D metal chalcogenides are reviewed, emphasising the effects of
1103 the precursor(s), solvent and electrode designs. Emerging work using nano-band electrodes to
1104 promote in-plane 2D layer growth into 'device-ready' electrode structures is highlighted.

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